AMAT CMP
TUNGSTEN AND OXIDE SLURRY CLEAN

OBJECTIVE:
TO ELIMINATE THE PROBLEMS ASSOCIATED WITH USING SCOTCH-BRITE™ AND CERAMIC SCRAPPERS TO REMOVE TUNGSTEN AND OXIDE SLURRY FROM CMP EQUIPMENT

PROBLEM:
- Using Scotch-Brite™ and/or ceramic scrappers to clean CMP tools
- Drying CMP pedestal with non-absorbent fab polyester wipes

RISK:
- RISK of Scotch-Brite™ residuals left inside CMP tool causing scratches on processed wafers
- Difficult to remove slurry built-up on Lexan panels without scratching panel
- Difficult to glue down new polishing pad onto wet surface

SOLUTION:
- **Diamond ScrubPAD** – Eliminates the use of Scotch-Brite™ and/or ceramic scrappers to remove slurry build up from CMP equipment
- **ScrubCLEAN® Sponge** – Effectively cleans Lexan panels without scratching surface
- **UltraSOLV® Sponge** – Effectively dries CMP pedestal

*Scotch-Brite™ is a registered trademark of 3M Corporation.*
Why risk the dangers of using Scotch-Brite™?

Scotch-Brite™ Residual

Diamond ScrubPAD Residual

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**TUNGsten SLurry CLEAN:** Diamond Grit ScrubPAD

Diamond ScrubPAD  Scotch-Brite™*

Diamond ScrubPAD Gently Removing Slurry Build-Up

Clean CMP Part

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**OXIDE SLURRY CLEAN:** Diamond Grit ScrubPAD

**CMP POLISHING HEAD CLEAN:** Diamond Grit ScrubPAD
LEXAN PANEL CLEAN: FS206 ScrubCLEAN® Sponge

CMP Lexan Panel Coated With Slurry

ScrubCLEAN® Gently Removing CMP Slurry

Clean Lexan Panel